

10/593830
IAP9 Rec'd PCT/PTO 22 SEP 2006

DOCKET NO.: 296431US2PCT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: Hisao IGARASHI, et al.

SERIAL NO.: NEW U.S. PCT APPLICATION

FILED: HEREWITH

INTERNATIONAL APPLICATION NO.: PCT/JP05/06108

INTERNATIONAL FILING DATE: March 30, 2005

FOR: PROBE APPARATUS, WAFER INSPECTING APPARATUS PROVIDED WITH THE
PROBE APPARATUS AND WAFER INSPECTING METHOD

REQUEST FOR PRIORITY UNDER 35 U.S.C. 119
AND THE INTERNATIONAL CONVENTION

Commissioner for Patents
Alexandria, Virginia 22313

Sir:

In the matter of the above-identified application for patent, notice is hereby given that
the applicant claims as priority:

<u>COUNTRY</u>	<u>APPLICATION NO</u>	<u>DAY/MONTH/YEAR</u>
Japan	2004-102948	31 March 2004

Certified copies of the corresponding Convention application(s) were submitted to the
International Bureau in PCT Application No. PCT/JP05/06108. Receipt of the certified
copy(s) by the International Bureau in a timely manner under PCT Rule 17.1(a) has been
acknowledged as evidenced by the attached PCT/IB/304.

Respectfully submitted,
OBLON, SPIVAK, McCLELLAND,
MAIER & NEUSTADT, P.C.



Marvin J. Spivak
Attorney of Record
Registration No. 24,913
Surinder Sachar
Registration No. 34,423

Customer Number

22850

(703) 413-3000
Fax No. (703) 413-2220
(OSMMN 08/03)